



12179-P098US

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application: Iwamatsu

Serial No.: 09/836,857

Filed: April 17, 2001

Art Unit: 2881

Examiner: David Vanore

For: ELECTRON BEAM DUPLICATION LITHOGRAPHY METHOD AND APPARATUS

**AMENDMENT UNDER 37 C.F.R. §1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action having a mailing date of January 29, 2003 (Paper No. 7), with a three-month shortened statutory period for response set to expire on April 29, 2003, and hereby extended to June 30, 2003 by the attached Petition for Extension of Time, please amend the above-identified Application as follows:

**CERTIFICATION UNDER 37 C.F.R. § 1.8**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on June 30, 2003.

Signature

Toni Stanley

(Printed name of person certifying)

PATENT

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